



Docket No.: 21.1837

#34/F  
9-10-02  
*[Signature]*

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

Munetaka TAKEUCHI, et al.

Serial No. 08/889,440

Group Art Unit: 2123

Confirmation No. 3473

Filed: July 8, 1997

Examiner: H. Jones

For: APPARATUS AND METHOD FOR SIMULATING PHENOMENA OF A PARTICLE OF  
SUBSTRATE PARTICLES AND ADSORBATE PARTICLES

RECEIVED  
SEP 06 2002  
Technology Center 2100

AMENDMENT

Assistant Commissioner for Patents  
Washington, D.C. 20231

Sir:

This is in response to the Office Action mailed on March 22, 2002, and having a period for response set to expire on June 22, 2002. A Petition for a two-month extension of time, together with the requisite fee for the same, is submitted herewith, thereby extending the period for response to August 22, 2002. Therefore, this Amendment is timely filed, with a two-month extension of time by August 22, 2002.

The following amendments and remarks are respectfully submitted. Reconsideration of the claims is respectfully requested.

IN THE CLAIMS:

Please AMEND claims 1, 16, 20, 23, and 24 in accordance with the following:

1. (AS FIVE TIMES AMENDED) An apparatus for simulating phenomena of a particle formed of adsorbate particles and substrate particles, comprising:
- a kinetic condition setting unit which sets information for defining a plurality of generation periods and a corresponding number of adsorbate particles to be generated during each generation period wherein the information can include a position of a corresponding emission source, a temperature, a chemical composition of the particle, a region, a physical condition, a velocity of each atom forming the particle, and a direction; and

FI